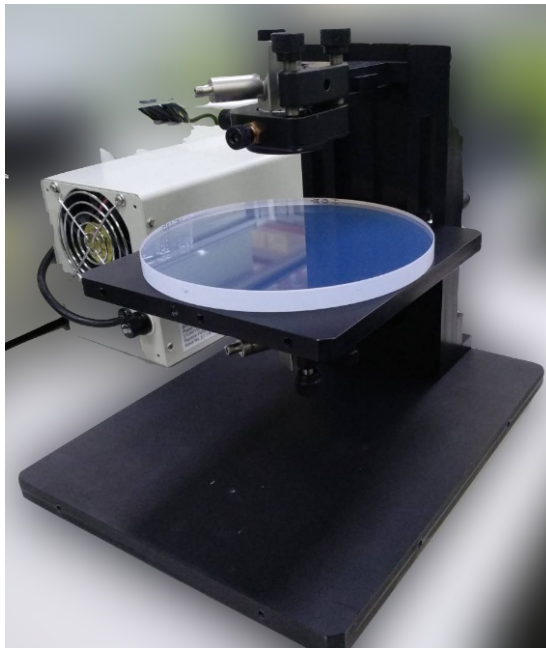


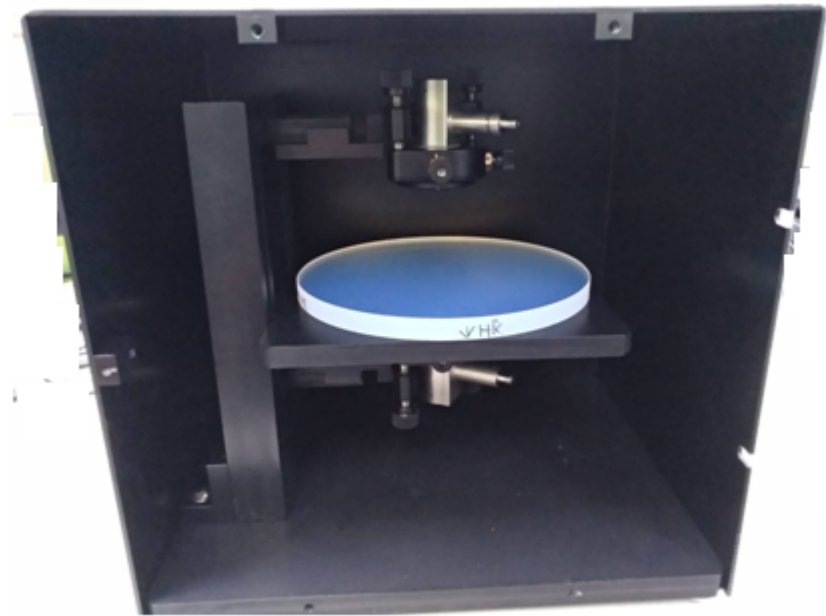
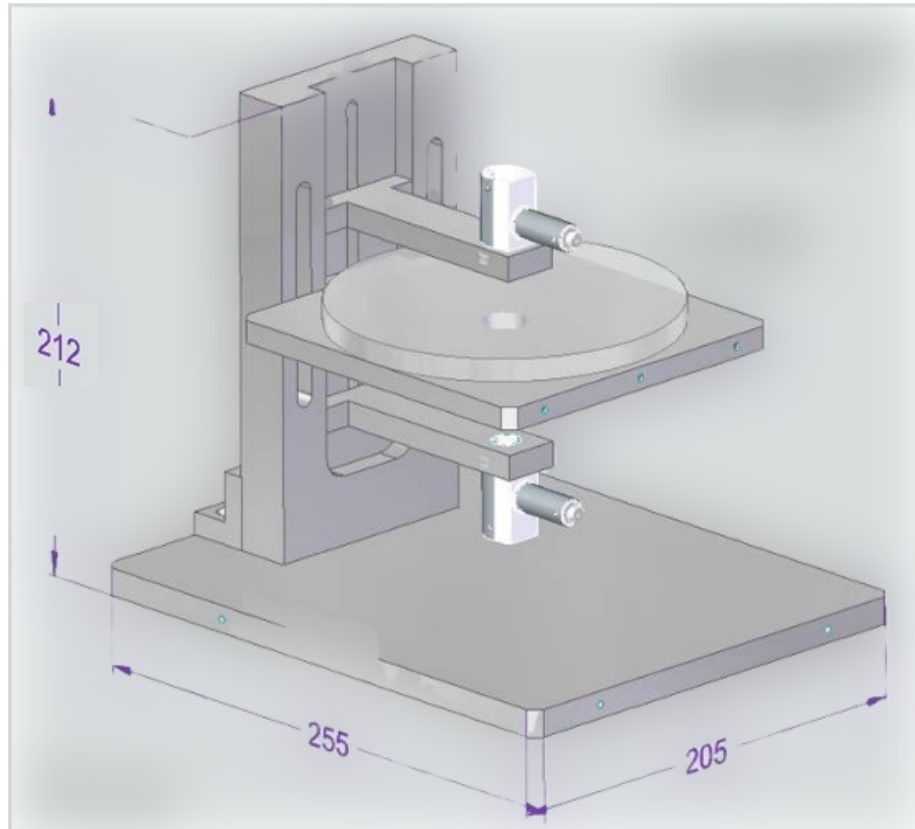
统新自行研发薄膜量测仪 Apogee Measuring System (AMS)



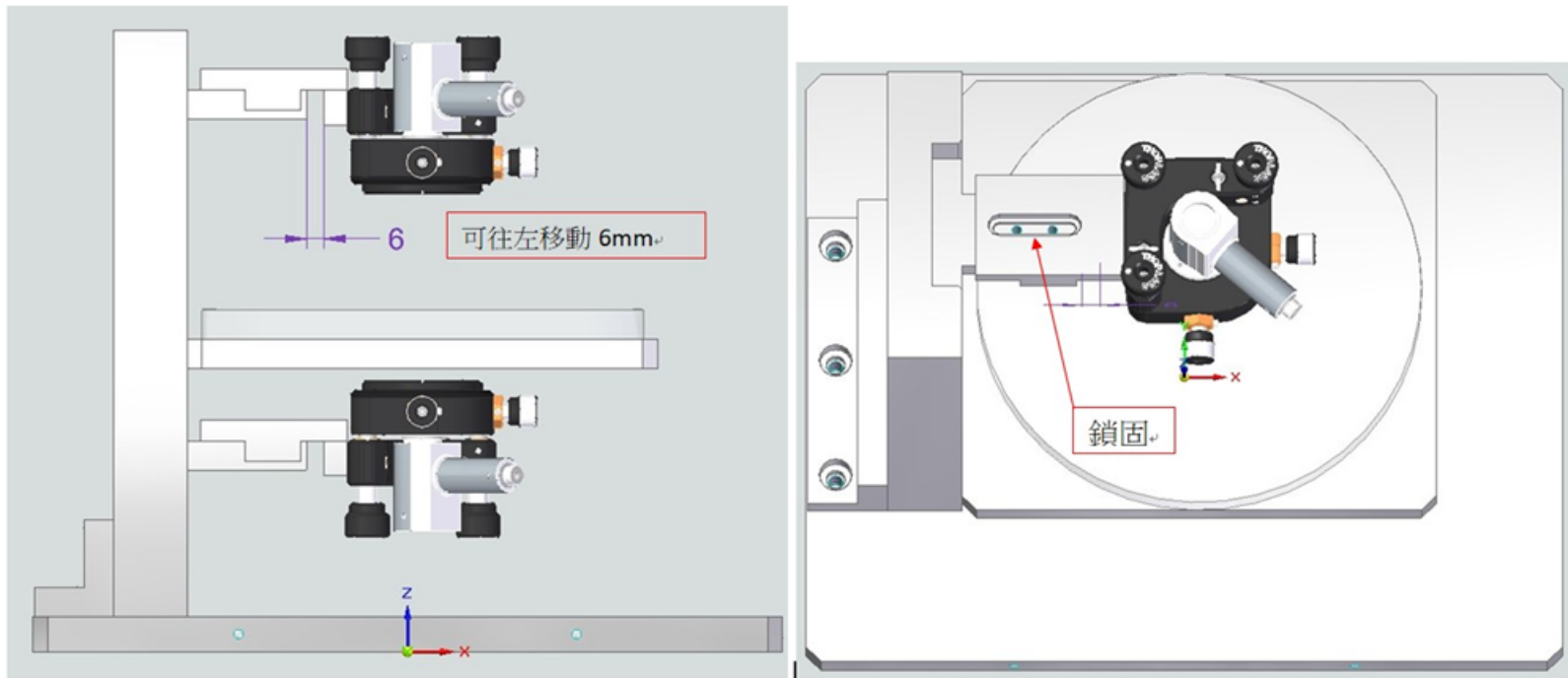
ACMS简介

- 膜厚度测(10 nm-25 μm)
- 折射率N、吸收系数K量测
- 广波域量测(450-1000 nm, 1000-1600 nm)
- 反射率或穿透率光谱量测
- 光谱分辨率 ~ 1 nm
- 光谱重复性 $< 0.03\%$
- 多层膜厚度D量测(厚度误差 < 2 nm, 精准度 < 0.1 nm)
- 折射率误差 < 0.1
- 有机高分子材料、金属氧化物、氮化物、半导体材料、介电质材料等
- 基板尺寸平台皆可客制 (标准品: 4")

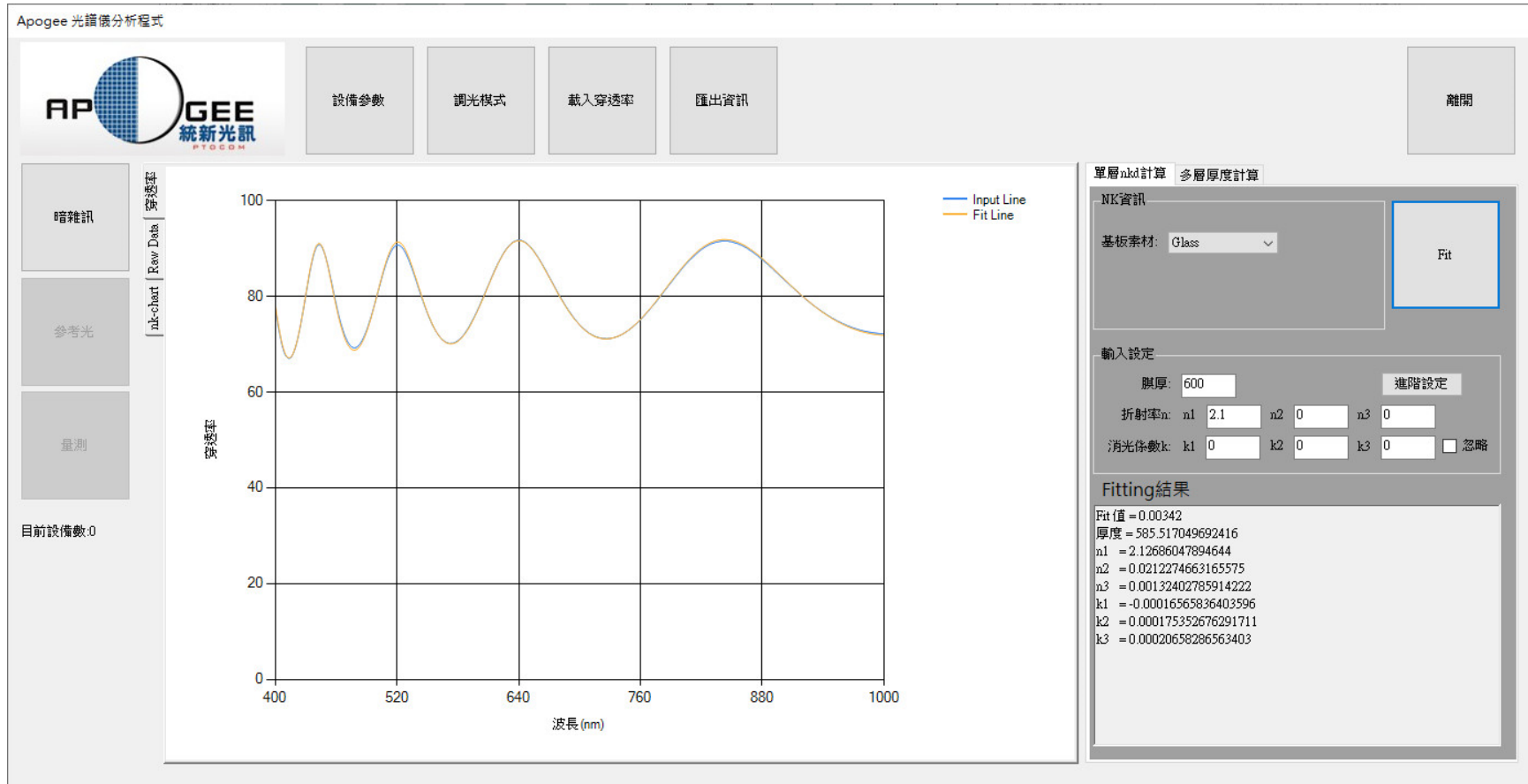
ACMS架构



ACMS微調整座



ACMS操作软件



ACMS操作软件

FormSetting

Prepare Measurement Data

	Serial Number	Detector Type	Total Pixels	Start Pixel	Stop Pixel	Integration Time [ms]	Integration Delay [ms]	Averaging
▶	2002069U1	HAMG9208_512	512	65	310	2.00	0	30

參數設定

設備序號: 2002069U1

Integration Time [ms]: 2.00

Integration Delay [ms]: 0.00

Start Pixel: 65 對應波長: 1400.759

Stop Pixel: 310 對應波長: 1600.385

Average Num: 30

Smoothing: 0

讀取 EEPROM 寫入 EEPROM 設定

ExportForm

路徑: C:\Users\31320\Desktop

檔名: ExportData_20210317_111437

匯出項目

波長 穿透率(%) 參考光 暗雜訊 量測值

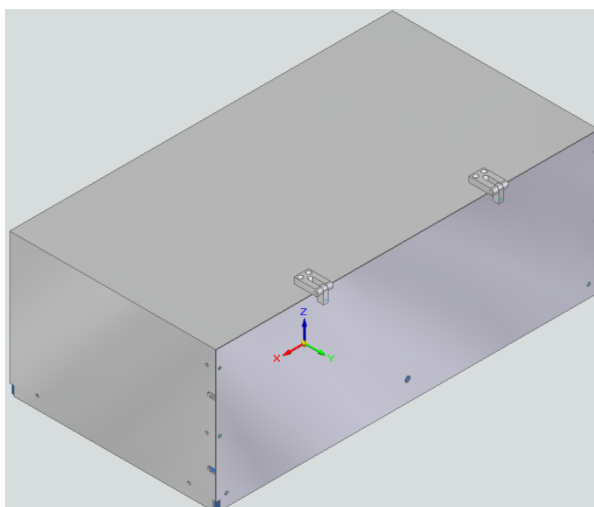
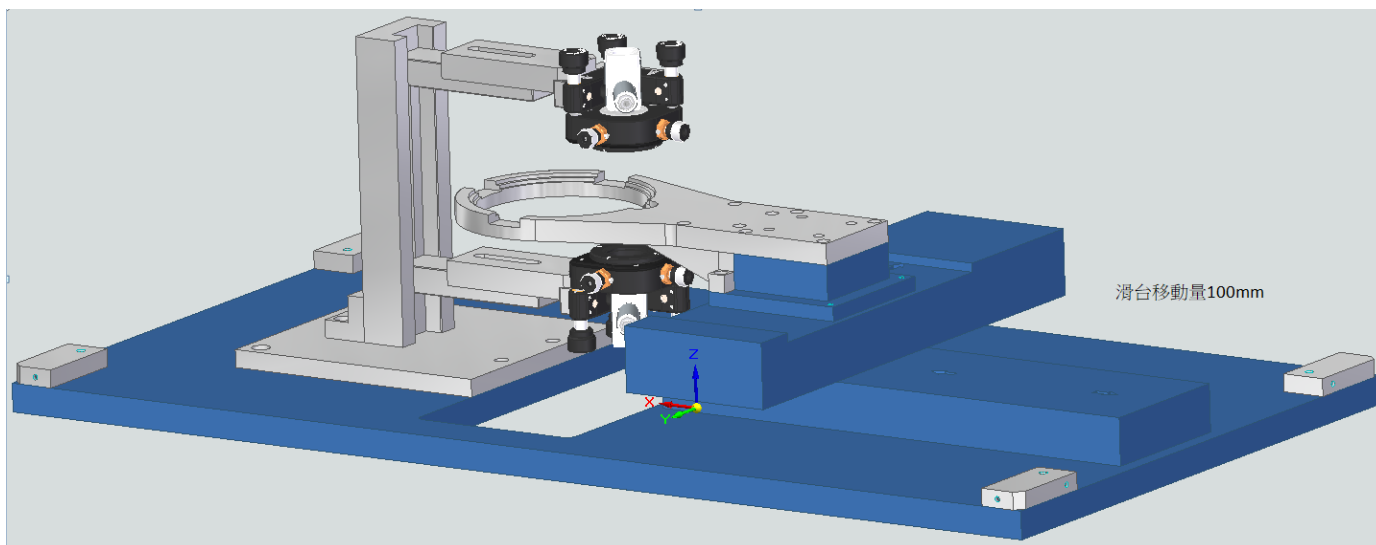
分析報告: nkd資料分析

將資料整理成每1nm(波長)一筆

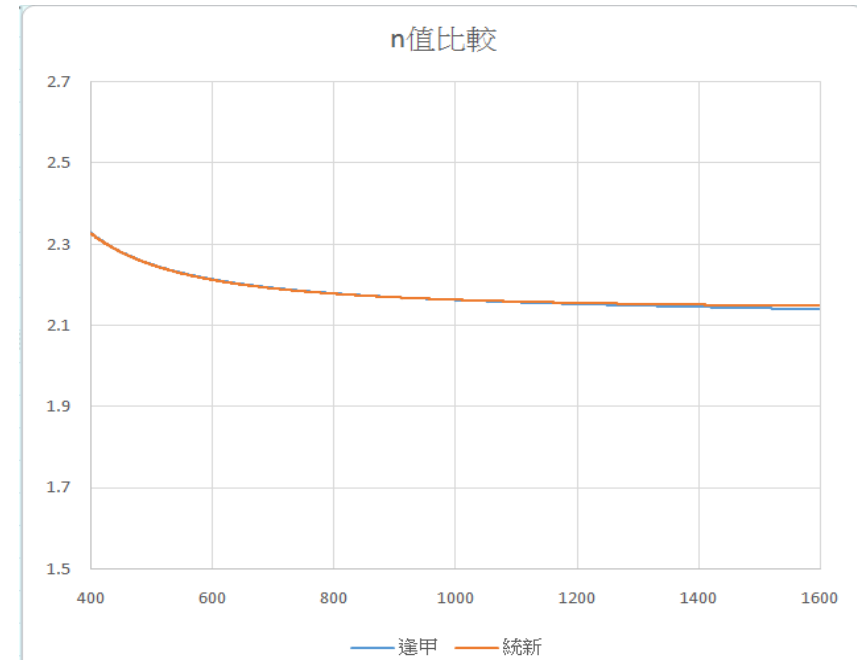
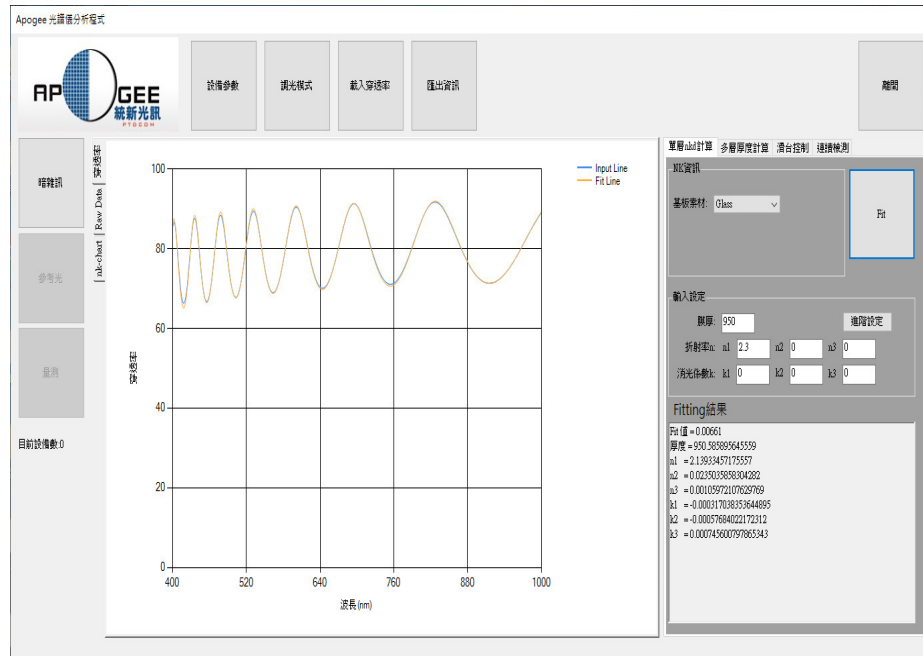
存檔 離開

確定

自动量测点位加装

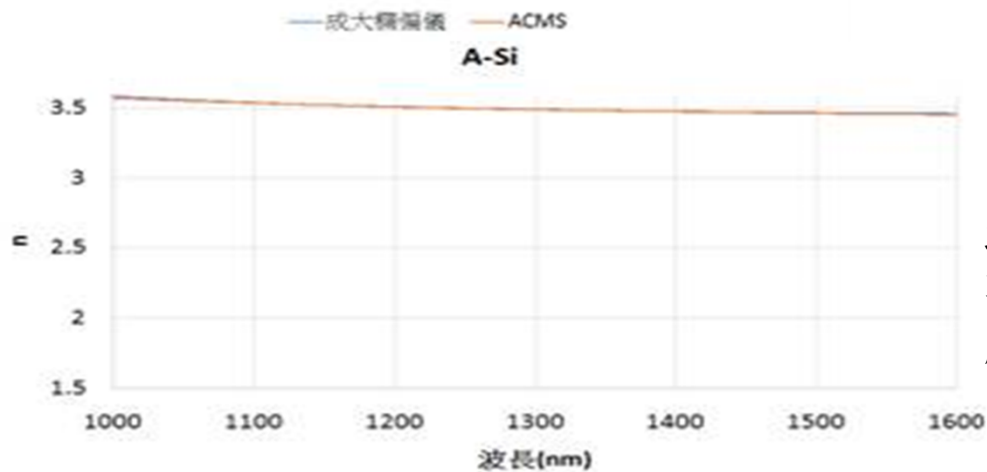
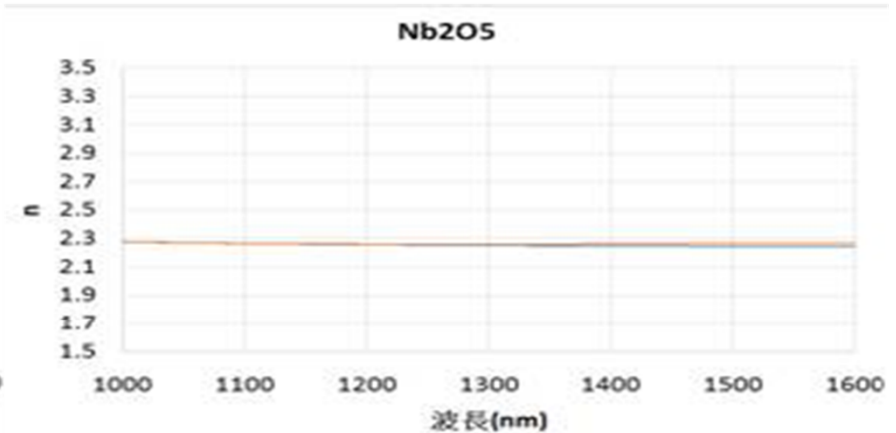
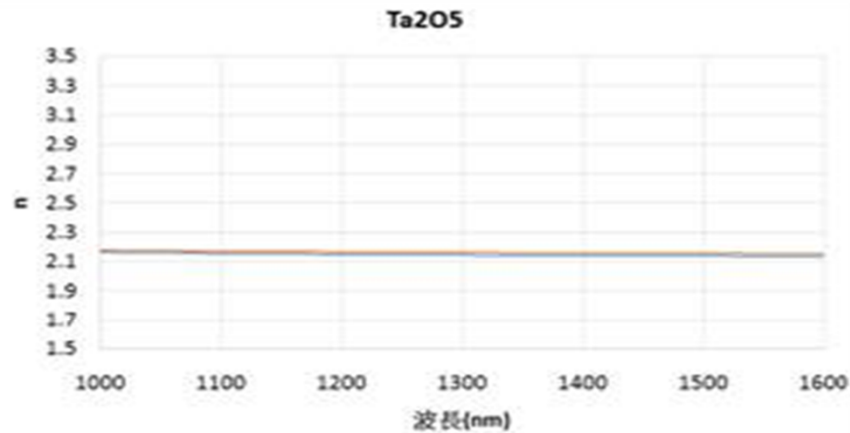


量测试验



Ta2O5 单层膜光谱量测和Angilent Cary7000一致
跟J. A Woollam m-2000 椭偏仪相较计算折射率差异<0.1
厚度差异<2nm

量测试验II



跟J. A Woollam m-2000椭圆仪相比较计算折射率差异<0.1
厚度差异<2nm